



IRW

PATENT  
81872.0055

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Yosuke INOMATA

Serial No: 10/762,676

Filed: January 22, 2004

For: MULTICRYSTALLINE SILICON  
SUBSTRATE AND PROCESS FOR  
ROUGHENING SURFACE  
THEREOF

Art Unit: 1765

Examiner: Not Assigned

**STATUS REQUEST**

Mail Stop Status Inquiry  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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March 22, 2005

Date of Deposit

Sheila Goldner

Name

*Sheila Goldner* 03/22/05

Signature

Date

Dear Sir:

This application was filed on January 22, 2004 and receipt by the U.S. Patent and Trademark Office was acknowledged in the Filing Receipt dated April 27, 2004. However, no Office Action has yet been received. Accordingly, Applicants request to be advised of the status of the application, including an indication of when the patent application is expected to be examined.

Please send the undersigned a Status Report on this application.

Respectfully submitted,  
HOGAN & HARTSON L.L.P.

Date: March 22, 2005

By:

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